



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Takua NAKAMURA

Group Art Unit: 3739

Application No.: 10/080,712

Examiner: David M. Shay

Filed: February 25, 2002

Docket No.: 111856

For: METHOD FOR ASSESSING IRRADIATION INTENSITY OF A LASER BEAM, AN APPARATUS FOR ASSESSING IRRADIATION INTENSITY USED UNDER THIS METHOD, AND A LASER BEAM IRRADIATION SYSTEM

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the September 24, 2003 Office Action, the period for response being extended by the enclosed Petition for Extension of Time, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.

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